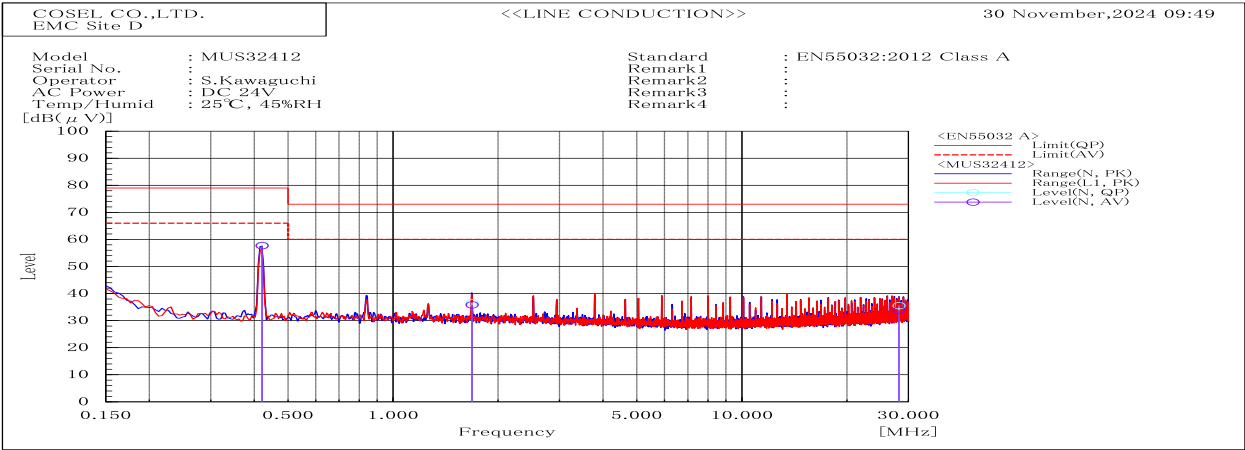
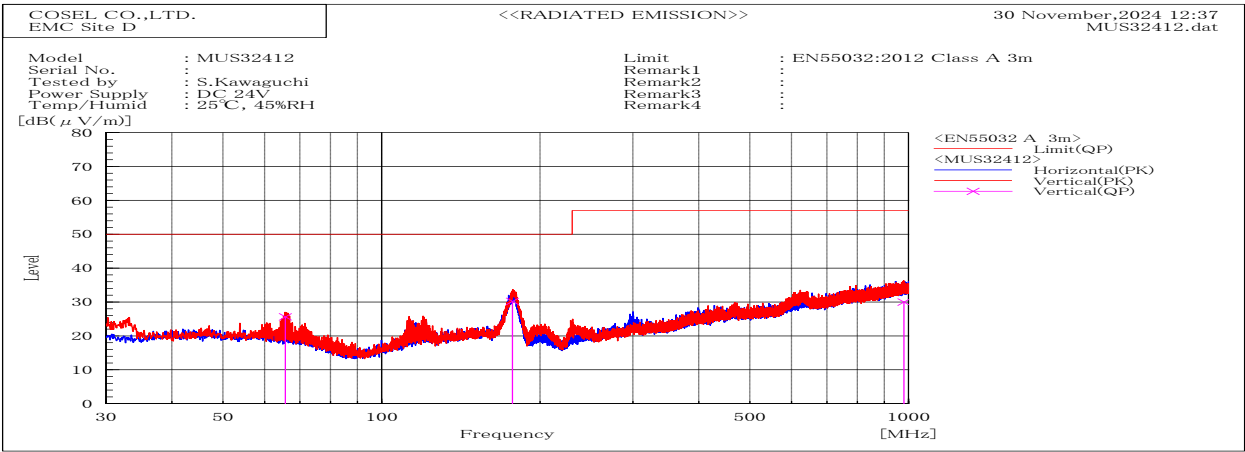


DATA SHEET		Date	30-Nov-24
Model	MUS32412	Temp.	25 degreeC
Test	EMI Line conduction & Radiated emission	Humid.	45 %RH
		Tested by	S.Kawaguchi



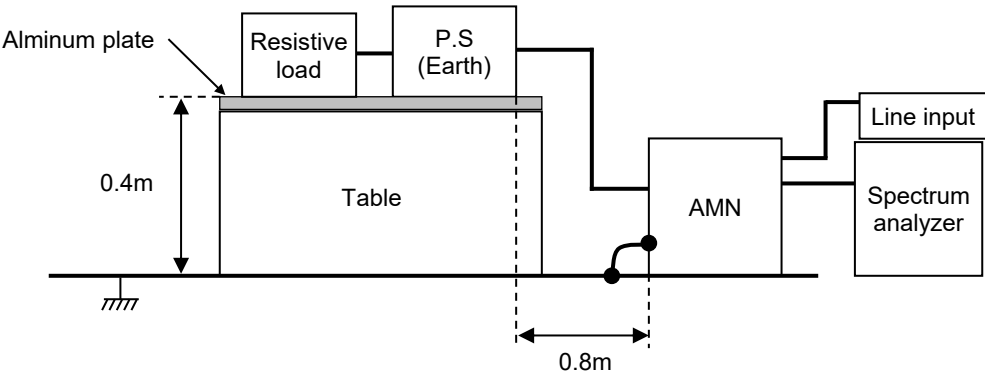
Frequency	Line	Level		Limit		Margin		Pass/Fail	Remark
MHz		dB(μV)		dB(μV)		dB			
		QP	AV	QP	AV	QP	AV		
0.421	N	57.8	57.7	79	66	21.2	8.3	Pass	
1.685	N	36.7	35.8	73	60	36.3	24.2	Pass	
28.216	N	35.5	33.9	73	60	37.5	26.1	Pass	



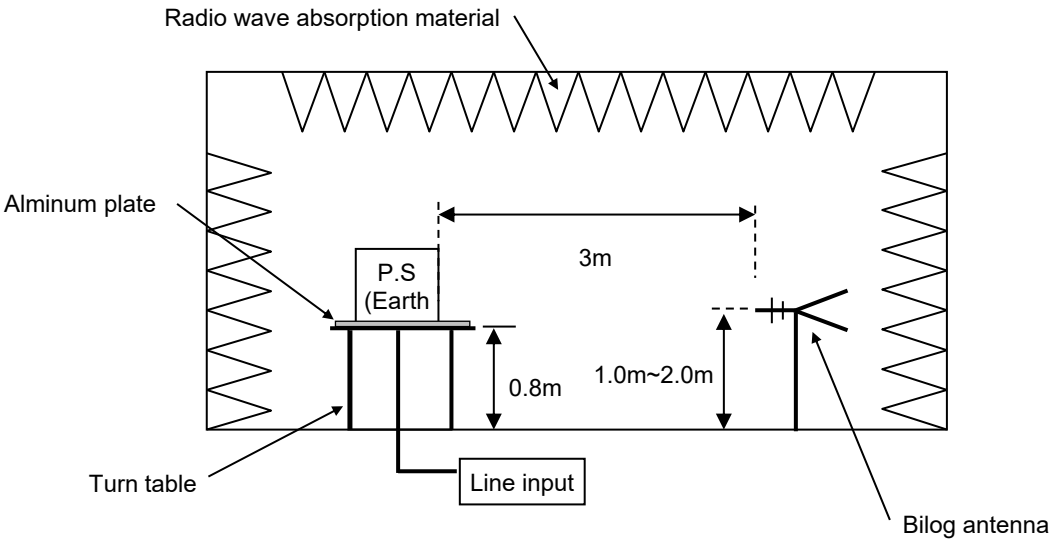
Frequency MHz	Polarization	Stability	Level	Limit	Margin	Pass/Fail	Height cm	Angle deg	Remark
			dB(uV/m) QP	dB(uV/m) QP	dB QP				
177.142	V	Stable	30.2	50	19.8	Pass	100.2	230.8	
65.699	V	Stable	25.6	50	24.4	Pass	100.4	0	
980.168	V	Stable	30	57	27	Pass	100.4	348	

DATA SHEET		Date	30-Nov-24
Model	Circuit used for measurement	Temp.	25 degreeC
Test	EMI Line conduction & Radiated emission	Humid.	45 %RH
		Tested by	S.Kawaguchi

1. Line conduction



2. Radiated emission

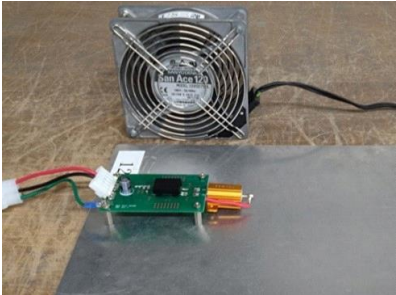


Conditions

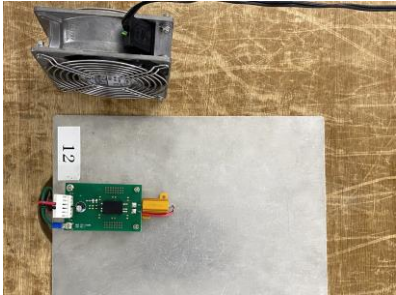
Test : EMI  
Model Name: MUS3□□

○Photographs of Test Set-Up

LINE CONDUCTION



RADIATED EMISSION



○Testing circuitry

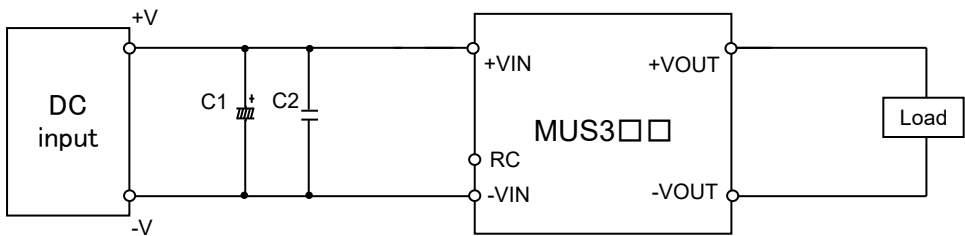


Fig.1 MUS305□, MUS312□, MUS324□ Testing circuitry

- |      |         |                 |   |
|------|---------|-----------------|---|
| C1 : | MUS305□ | 16V 220 $\mu$ F | Electric capacitor (UPWseries NICHICON)                 |
|      | MUS312□ | 50V 100 $\mu$ F | Electric capacitor (UPWseries NICHICON)                 |
|      | MUS324□ | —               |   |
| C2 : | MUS305□ | 16V 22 $\mu$ F  | Ceramic capacitor (GRM31CC71C226M MURATA MANUFACTURING) |
|      | MUS312□ | 25V 22 $\mu$ F  | Ceramic capacitor (C3216JB1E226MT TDK)                  |
|      | MUS324□ | 50V 10 $\mu$ F  | Ceramic capacitor (C3216X7R1H106KT TDK)                 |

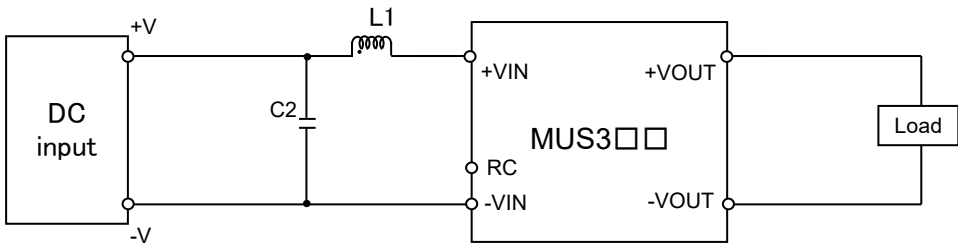


Fig.2 MUS348□ Testing circuitry

- |      |         |                  |  |
|------|---------|------------------|--|
| C2 : | MUS348□ | 100V 2.2 $\mu$ F | Ceramic capacitor (C3216X7S2A225KT TDK)        |
| L1 : | MUS348□ | 520mA 15 $\mu$ H | Inductor (LQH32PN150MN0L MURATA MANUFACTURING) |